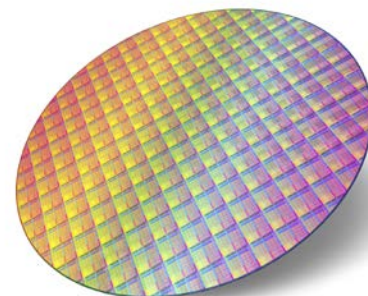


Nanoscale Plasma Processing Seminar

A Workshop presented by:
Oxford Instruments Plasma Technology & MTL

Wednesday 5th December 2012

Venue: Massachusetts Institute of Technology, Cambridge, MA



Morning programme

9:00-9:30	Registration and coffee	
9:30-10:00	Welcome	<i>MIT & Oxford Instruments</i>
10:00-10:30	ALD Applications	<i>Prof. Erwin Kessels, Technical University Eindhoven, Netherlands</i>
10:30-11:00	An Overview of Plasma ALD Process	<i>Chris Hodson Oxford Instruments Plasma Technology</i>
11:00-11:15	Break	
11:15-11:45	Electrical characterization of film properties	<i>Winston Chern, MTL</i>
11:45-12:15	MEMS Process	<i>Mark McNie, Oxford Instruments Plasma Technology</i>
12.15-1.15	Lunch break	

Afternoon programme

1:15-1:45	Nanoscale Dielectric Etching	<i>Vince Genova, Cornell University</i>
1:45-2:15	Topic TBC	<i>Jerome Lin, MTL</i>
2:15- 2:30	Break	
2:30-3:00	PECVD (inc 450mm) & TEOS	<i>Chris Hodson, Oxford Instruments Plasma Technology</i>
3:00-3:30	Oxford Instruments Posters and questions	<i>Oxford Instruments Applications and Product specialists</i>
3:30-3:45	Wrap up and close	

Poster session: Oxford Instruments process and technology posters will be shown during the break periods

Social event: All delegates are invited to join the hosts for a Drinks social after the event (4.00pm -6.00pm) at a venue to be confirmed near MIT

To book a place, contact: Nancy Crouch, Oxford Instruments Plasma Technology, USA
nancy.crouch@oxinst.com or Tollfree: +1 800 447 4717

There is no charge for this event, however booking is essential

About MIT

The mission of MIT is to advance knowledge and educate students in science, technology, and other areas of scholarship that will best serve the nation and the world in the twenty-first century.

The Institute is committed to generating, disseminating, and preserving knowledge, and to working with others to bring this knowledge to bear on the world's great challenges. MIT is dedicated to providing its students with an education that combines rigorous academic study and the excitement of discovery with the support and intellectual stimulation of a diverse campus community. We seek to develop in each member of the MIT community the ability and passion to work wisely, creatively, and effectively for the betterment of humankind.

About MTL

The Microsystems Technology Laboratories (MTL) at MIT is an interdepartmental laboratory supporting research and education in micro- and nano- systems. MTL was established in the mid-1980s inside the Electrical Engineering and Computer Science Department. Over the years, MTL has evolved and grown into an Interdepartmental laboratory reporting to the Dean of the School of Engineering, reaching across the entire Institute.

About Oxford Instruments Plasma Technology

Oxford Instruments Plasma Technology offers flexible, configurable process tools and leading-edge processes for the precise, controllable and repeatable engineering of micro- and nano-structures. Our systems provide process solutions for nanometre layer epitaxial growth of compound semiconductor material, etching of nanometre sized features and the controlled growth of nanostructures.

These solutions are based on core technologies in plasma-enhanced deposition and etch, ion-beam deposition and etch, atomic layer deposition and hydride vapour phase epitaxy. Products range from compact stand-alone systems for R&D, through batch tools and up to clustered cassette-to-cassette platforms for high-throughput production processing.

To book a place at the Seminar contact:

Nancy Crouch, Oxford Instruments Plasma Technology, USA
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Tollfree: +1 800 447 4717

Oxford Instruments Plasma Technology

- Plasma Etch & Deposition
- Atomic Layer Deposition
- Ion Beam Etch & Deposition
- Deep Silicon Etch

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www.oxford-instruments.com/plasma for more information

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